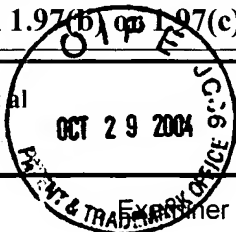


IFW

TRANSMITTAL OF INFORMATION DISCLOSURE STATEMENT (Under 37 CFR 1.97(b) or 1.97(c))	Docket No. P0387
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In Re Application Of: Erwan Le Roy et al



Application No. 10/789,336	Filing Date 02/27/2004	Examiner na	Customer No. na	Group Art Unit na	Confirmation No. 9033
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Title: **METHOD AND APPARATUS FOR THE IMPROVEMENT OF MATERIAL/VOLTAGE CONTRAST**

Address to:
 Commissioner for Patents
 P.O. Box 1450
 Alexandria, VA 22313-1450

37 CFR 1.97(b)

1. ☒ The Information Disclosure Statement submitted herewith is being filed within three months of the filing of a national application other than a continued prosecution application under 37 CFR 1.53(d); within three months of the date of entry of the national stage as set forth in 37 CFR 1.491 in an international application; before the mailing of a first Office Action on the merits, or before the mailing of a first Office Action after the filing of a request for continued examination under 37 CFR 1.114.

37 CFR 1.97(c)

2. ☐ The Information Disclosure Statement submitted herewith is being filed after the period specified in 37 CFR 1.97(b), provided that the Information Disclosure Statement is filed before the mailing date of a Final Action under 37 CFR 1.113, a Notice of Allowance under 37 CFR 1.311, or an Action that otherwise closes prosecution in the application, and is accompanied by one of:

☐ the statement specified in 37 CFR 1.97(e);

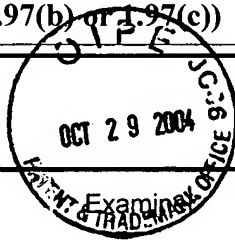
OR

☐ the fee set forth in 37 CFR 1.17(p).

TRANSMITTAL OF INFORMATION DISCLOSURE STATEMENT
(Under 37 CFR 1.97(b) or 1.97(c))

Docket No.
P0387

In Re Application: Erwan Le Roy et al



Application No. 10/789,336	Filing Date 02/27/2004	Examiner na	Customer No. na	Group Art Unit na	Confirmation No. 9033
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Title:

Payment of Fee

(Only complete if Applicant elects to pay the fee set forth in 37 CFR 1.17(p))

- ☐ A check in the amount of _____ is attached.
- ☐ The Director is hereby authorized to charge and credit Deposit Account No. _____ as described below.
- ☐ Charge the amount of _____
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Deborah W. Wenocur

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Signature

Dated: Oct. 25, 2004

Deborah W. Wenocur, Reg. No. 40,221

Agent for Applicant

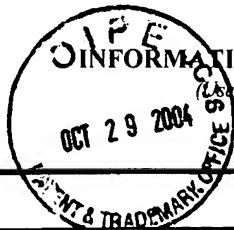
c/o Shelly Garrett

Credence Systems Corp

1421 California Circle

Milpitas, CA 95035

CC:

**INFORMATION DISCLOSURE CITATION**

(Use several sheets if necessary)

Docket Number (Optional)

P0387

Application Number

10/789,336

Applicant(s)

Erwan Le Roy et al

Filing Date

02/27/2004

Group Art Unit

na

U.S. PATENT DOCUMENTS

*EXAMINER INITIAL	REF	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
	1	5,948,217	09/07/1999	Winer et al	204	192.34	12/20/1996

U.S. PATENT APPLICATION PUBLICATIONS

*EXAMINER INITIAL	REF	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE

FOREIGN PATENT DOCUMENTS

	REF	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	Translation	
							YES	NO

OTHER DOCUMENTS

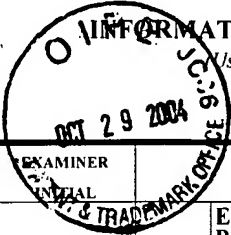
(Including Author, Title, Date, Pertinent Pages, Etc.)

	1	E.L. Cole, "Beam-Based Localization Techniques for IC Failure Analysis", Microelectronic Failure Analysis, Desk Reference 4th ed., R. Ross, C. Boit, D. Staab, editors (2001) ASM International Materials Park, OH, pp. 136-137
	2	V.S. Aliev and V.N. Kruchinin, "Development of Si(100) Surface Roughness at the Initial Stage of Etching in F2 and XeF2 Gases: Ellipsometric Study", Surface Scienc 442 (1999), pp 206-214

EXAMINER

DATE CONSIDERED

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Docket Number (Optional)

P0387

Application Number

10/789,336

Applicant(s)

Erwan Le Roy et al

Filing Date

02/27/2004

Group Art Unit

na

OTHER DOCUMENTS *(Including Author, Title, Date, Pertinent Pages, Etc.)*

E. I. Cole Jr., C. R. Bagnell, Jr., B. Davies, A. Neacsu, W. Oxford, S. Roy, and R. H. Propst, "A Novel Method for Depth Profiling and Imaging of Semiconductor Devices Using Capacitive Coupling Voltage Contrast", J. Appl. Phys, 62(12), 15 December 1987, pp 4909-4915

EXAMINER

DATE CONSIDERED

***EXAMINER:** Initial if citation considered, whether or not citation is in conformance with MPEP Section 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.